

**Attorney Docket: Serie 5444**

Application No: Not yet assigned

Applicant: Christian DUSSARRAT, et al.

Examiner: Unknown

Filed: Herewith

TC/A.U: Unknown

Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS AND  
SILICON OXYNITRIDE FILMS BY THERMAL CHEMICAL  
VAPOR DEPOSITION

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#### **PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Prior to an examination of the merits of the above-identified U.S. patent application under 37 C.F.R. § 1.115, please first amend the application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 3 of this paper.

**Remarks** begin on page 10 of this paper.